U.S. PATENT DOCUMENTS

5,726,073	A	3/1998	Zhang et al.	437/228
5,753,911	A	5/1998	Yasuda et al.	250/306
5,867,297	A	2/1999	Kiang et al.	359/198
5,872,880	A	2/1999	Maynard	385/88
5,881,198	A	3/1999	Haake	385/136
5,959,760	A	9/1999	Yamada et al.	359/224
5,969,848	A	10/1999	Lee et al.	359/298
5,995,334	A	11/1999	Fan et al.	360/106
5,998,906	A	12/1999	Jerman et al.	310/309
6,000,280	A	12/1999	Miller et al.	73/105
6,025,951	A	2/2000	Swart et al.	359/245
6,067,858	A	5/2000	Clark et al.	73/504.16
6,073,484	A	6/2000	Miller et al.	73/105
6,133,670	A	10/2000	Rodgers et al.	310/309
6,134,207	A	10/2000	Jerman et al.	369/112
6,137,941	A	10/2000	Robinson	385/140
6,201,629	B1	3/2001	McClelland et al.	359/223
6,212,309	B1	4/2001	Nguyen et al.	385/17
6,215,222	B1	4/2001	Hoen	310/309
6,253,612	B1	7/2001	Lemkin et al.	73/504.02
6,257,062	B1 *	7/2001	Rich	73/514.32
6,296,779	B1	10/2001	Clark et al.	216/66
6,301,403	B1	10/2001	Heanue et al.	385/18
6,329,737	B1	12/2001	Jerman et al.	310/309
6,330,102	B1	12/2001	Daneman et al.	359/290
6,360,035	B1	3/2002	Hurst, Jr. et al.	385/16
6,374,008	B2	4/2002	Solgaard et al.	385/17

OTHER PUBLICATIONS

"Optical Methods For Micromachine Monitoring And Feedback", F.M. Dickey et al., Sensors and Actuators, vol. 78, 1999, pp 220–235.

"A High Sensitivity Z–Axis Capacitive Silicon Microaccelerometer with a Torsional Suspension", Selvakumar et al., Journal of Microelectromechanical Systems, IEEE Inc., New York, vol. 7, No. 2, Jun. 1998, pp 192–200.

"MEMS Fabrication of High Aspect Radio Track–Following Micro Actuator for Hard Disk Drive Using Silicon On Insulator", B. H. Kim et al., Technical Digest of the IEEE International MEMS '99 Converence. 12th IEEE International Conference on Micro Electro Mechanical Systems. Orlando, FL, Jan. 17–21, 1999, IEEE International Micro Electro Mechanical Systems Converence, New York, NY, 1999, pp 53–56.

"Fabrication of Comb–Shaped Microactuator for Multi–Degrees–of–Freedom System", F. Fujikawa et al., Robotics, CIM and Automation, Emerging Technologies, San Diego, Nov. 9–13, 1992, Proceedings of the International Converence on Industrial Electronics, Control, Instrumentation and Automation (IECON), New York, NY, IEEE, US, vol. 2 Conf 18, Nov. 9, 1992, pp 990–995.

"Integrated Micro–Scanning Tunneling Microscope", Xu et al., Applied Physics Letters, American Institute of Physics, New York, vol. 67, No. 16, Oct. 16, 1995 pp 2305–2307.

"Vertical Comb Array MicroActuators", A. Selvakumar et al., Proceedings of the Workshop on Micro Electrical Mechanical Systems (MEMS), Amsterdam, New York, Jan. 29–Feb. 2, 1995, IEEE vol. Workshop 8 Jan. 29, 1995, pp 43–48, ISBN 0–7803–2504–4.

"Fabrication of a 3D Differential–Capacitive Acceleration Sensor by UV–LIGA", W. Qu et al., Sensors and Actuators 77 (1999), pp 14–20, Elsevier Science, 0924–4247/99/$.

"Integrating SCREAM Micromachined Devices with Integrated Circuits", K.A. Shaw, N.C. MacDonald, IEEE MEMS '96, San Diego, California 1996, IEEE Publication 0–7803–2985–6/96, pp 44–48.

"An electrostatically excited 2D–Micro–Scanning–Mirror with an in–plane configuration of the driving electrodes", H. Schenk et al., MEMS 2000, 13th Int. Micro Electro Mechanical Systems Conf, Miyazaki, Japan, p. 473–478 (2000).

"Damping of Micro Electrostatic Torsion Mirror Caused by Air–Film Viscosity", N. Uchida et al. No date.

"Single Crystal Silicon (SCS) MicroMirror Arrays using Deep Silicon Etching and IR Alignment", C.S.B. Lee et al. No date.

Zhimin Yao and Noel MacDonald, Single Crystal Silicon Supported Thin Film Micromirrors for Optical Applications, May 1997, P1408–1413.

Robert Conant et al., "A Flat High–Frequency Scanning Micromirror,"2000, P1–3.

* cited by examiner